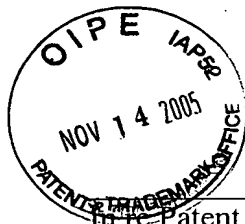


IFW

Docket No.: 8734.254.00-US  
(PATENT)



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Yun-Ho JUNG

Customer No.: 30827

Application No.: 10/705,891

Confirmation No.: 6104

Filed: November 13, 2003

Art Unit: 1756

For: MASK FOR LASER IRRADIATION AND  
APPARATUS FOR LASER  
CRYSTALLIZATION USING THE SAME

Examiner: Stephen D. Rosasco

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE TO RESTRICTION REQUIREMENT**

Dear Sir :

In response to the restriction requirement set forth in the Office Action mailed September 14, 2005, (Paper No. 20050907), Applicant hereby provisionally elects Group I, (Claims 1-24), for continued examination.

The Examiner has required restriction between Group I (Claims 1-24) and Group II (Claims 23-25).

An action on the merits of the claims relating to the above election and a Notice of Allowance thereof are respectfully requested.

Applicant hereby authorizes the Commissioner of Patents to charges any fees necessary to complete this filing, including any fees required under 37 C.F.R. §1.136 for any necessary Extension of Time to make the filing of the attached documents timely, or credit any overpayment in fees, to Deposit Account No. 50-0911. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. §1.136 for the necessary extension of time. Two copies of this sheet are enclosed.

Dated: November 14, 2005

Respectfully submitted,

By Valerie P. Hayes  
Valerie P. Hayes  
Registration No.: 53,005  
McKenna Long & Aldridge LLP  
1900 K Street N.W.  
Washington, D.C. 20006  
Voice: 202-496-7500  
Fax: 202-496-7756  
Attorneys for Applicant